

2015 International Workshop on EUV Lithography Makena Beach & Golf Resort, Maui, Hawaii June 15-19, 2015

FIRST CALL FOR PAPERS

We are inviting presentations and poster papers for the 2015 International Workshop on EUV Lithography, to be held June 15-19 at the Makena Beach Golf Resort in Maui, Hawaii. This workshop, now in its eighth year, is focused on the fundamental science of EUV Lithography (EUVL). A smaller group setting suitable for networking and brainstorming, with a focus on fundamentals, sets this conference apart from other larger conferences based on the commercial aspects of EUVL.

Technology review papers and presentations with innovative approaches to current EUV Lithography-related technical challenges are encouraged. EUV Lithography-related topics covered under this workshop include source for high volume manufacturing (HVM) and metrology, FEL based sources for EUVL, exposure tools, masks, optics, resist, contamination, metrology, patterning and cost of ownership. Papers on combinations of EUVL with multiple patterning, manufacturing readiness of EUVL and directed self-assembly (DSA) are also welcome.

The workshop will be preceded by an EUV Lithography Short Course on June 15. Registration for the workshop begins on June 16, followed by presentations, panel discussions and a poster session on June 17 and 18. The workshop will conclude June 19 with a Steering Committee meeting open to all workshop attendees. The keynote speakers for the 2015 workshop will be announced soon on our website www.euvlitho.com.

The 2015 International Workshop on EUV Lithography is organized by EUV Litho, Inc.

Instructions for Submissions and Deadlines

Please submit abstracts of less than 200 words and indicate whether an oral or poster paper is preferred. Please also include each author's full name, e-mail address, affiliation and mailing address, together with a brief biography and photograph for the presenting author. Abstracts should be submitted via email to abstracts@euvlitho.com.

The deadline for abstract submission is March 13, 2015. Authors will be notified by March 31 or earlier if their abstracts have been accepted for an oral or poster paper.

Contact Information

For meeting-related issues please contact: meeting.planner@euvlitho.com

For technical questions, please contact: vivek.bakshi@euvlitho.com